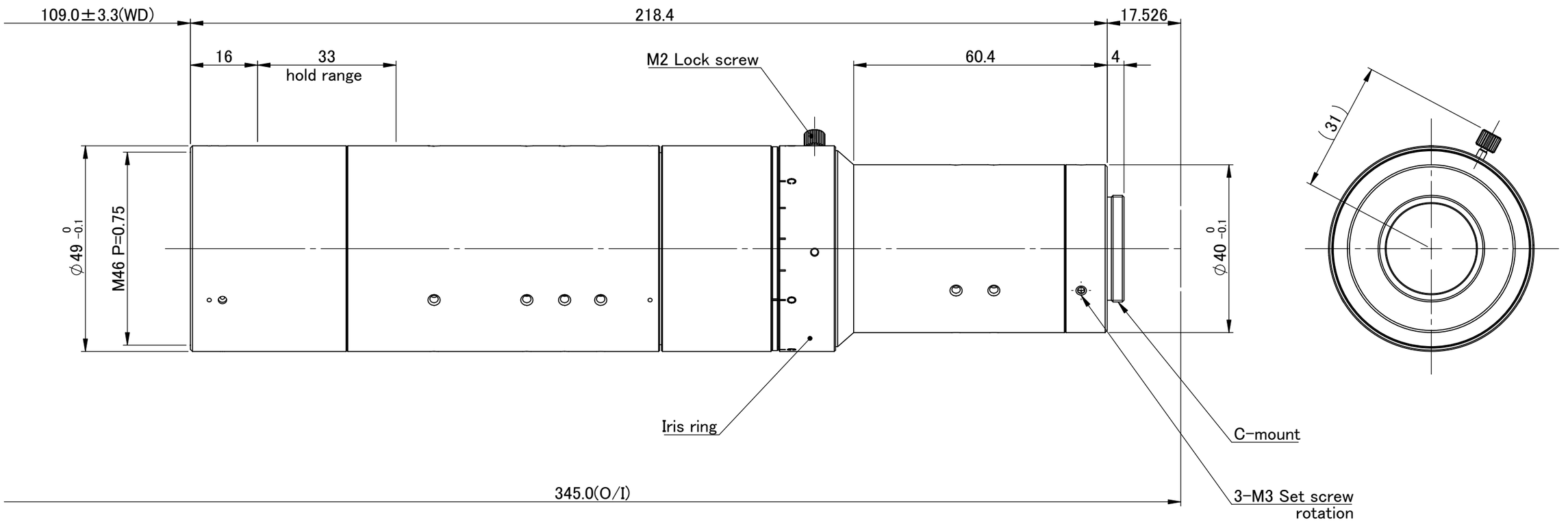
Confidential



△×			
NO. ×	REVISION	DATE	NAME

TREATMENT 処理	–			MATERIAL	–	UNIT	METHOD		
				CHAMFER	–				
TREATMENT CONTACT 処理接点	–			FINISHING	–	mm			
				DECENTRATION	–				
APPROVED	CHECKED	DESIGNED	DRAWN	TOLERANCE	–	REMARK	VS-TCTV1-110/S		
鈴木(利)	内川	千嶋	千嶋	ANGLE	–	NAME	DRAWING		
				SCALE	1:1				
				DATE	2026.03.16	DRAW NO.	M2170C-A00100		

Rev01